CLAIMS

What is claimed is:

1. In a plasma processing system, a method of removing a set of particles from a set of structures including yttrium oxide, comprising:

exposing said set of structures to a first solution including an oxidizer for a first period;

removing said set of structures from said first solution;

exposing said set of structures to a second solution including a keytone reagent for a second period;

removing said set of structures from said second solution; and mechanically rubbing a surface of said set of structures with a third solution including a first set of acids for a third period.

2. The method of claim 2, further including the steps of:

exposing said set of structures to a fourth solution including a second set of acids for a fourth period; and

exposing said set of structures to a fifth solution including a first set of alkalines for a fifth period.

- 3. The method of claim 2, wherein said step of immersing said set of structures in said first solution for a first period further includes mechanically rubbing said set of structures with an abrasive pad.
- 4. The method of claim 2, wherein said step of removing said set of structures from said first solution further includes rinsing said set of structures with de-ionized water.
- 5. The method of claim 4, further including drying said set of structures with a filtered inert gas.
- 6. The method of claim 5, wherein said filtered inert gas comprises nitrogen.

- 7. The method of claim 2, wherein said step of exposing said set of structures to said second solution for a second period further includes cleaning said set of structures ultrasonically.
- 8. The method of claim 2, wherein after said step of exposing said set of structures in said second solution for a second period, said set of structures are rinsed and mechanically rubbed with an alcohol.
- 9. The method of claim 2, wherein said step of removing said set of structures from said second solution further includes rinsing said set of structures with de-ionized water.
- 10. The method of claim 9, further including drying said set of structures with a filtered inert gas.
- 11. The method of claim 10, wherein said filtered inert gas comprises nitrogen.
- 12. The method of claim 11, wherein said step of removing said set of structures from said third solution further includes rinsing said set of structures with de-ionized water.
- 13. The method of claim 12, further including drying said set of structures with a filtered inert gas.
- 14. The method of claim 13, wherein said filtered inert gas comprises nitrogen.
- 15. The method of claim 2, wherein said step of removing said set of structures from said forth solution further includes rinsing said set of structures with de-ionized water.
- 16. The method of claim 15, further including drying said set of structures with a filtered inert gas.
- 17. The method of claim 16, wherein said filtered inert gas comprises nitrogen.

- 18. The method of claim 11, wherein said step of removing said set of structures from said fifth solution further includes rinsing said set of structures with de-ionized water.
- 19. The method of claim 15, further including drying said set of structures with a filtered inert gas.
- 20. The method of claim 16, wherein said filtered inert gas comprises nitrogen.
- 21. The method of claim 2, wherein said oxidizer comprises H₂O₂.
- 22. The method of claim 2, wherein said second solution comprises H₂O₂.
- 23. The method of claim 22, wherein said H_2O_2 comprises from about 10% to about 30% of said second solution.
- 24. The method of claim 22, wherein said H_2O_2 comprises from about 20% to about 30% of said second solution.
- 25. The method of claim 22, wherein said H_2O_2 comprises about 30% of said second solution.
- 26. The method of claim 2, wherein said first period comprises 30 minutes.
- 27. The method of claim 2, wherein said keytone reagent comprises acetone.
- 28. The method of claim 2, wherein said second period comprises 5 minutes.
- 29. The method of claim 2, wherein said third solution comprises H_2O_2 .
- 30. The method of claim 2, wherein said first set of acids comprises HF.
- 31. The method of claim 30, wherein said HF comprises from about 2% to about 33% of said third solution.

- 32. The method of claim 30, wherein said HF comprises from about 2% to about 25% of said third solution.
- 33. The method of claim 30, wherein said HF comprises of about 2% of said third solution.
- 34. The method of claim 2, wherein said first set of acids comprises HNO₃.
- 35. The method of claim 34, wherein said HNO₃ comprises from about 2% to about 33% of said third solution.
- 36. The method of claim 34, wherein said HF comprises from about 2% to about 25% of said third solution.
- 37. The method of claim 34, wherein said HF comprises of about 2% of said third solution.
- 38. The method of claim 2, wherein said third period comprises 1 minute.
- 39. The method of claim 2, wherein said forth solution comprises H₂O
- 40. The method of claim 2, wherein said second set of acids comprises CH₃COOH.
- 41. The method of claim 40, wherein said CH₃COOH. comprises from about 2% to about 10% of said forth solution.
- 42. The method of claim 40, wherein said CH₃COOH. comprises from about 2% to about 6% of said forth solution.
- 43. The method of claim 40, wherein said CH₃COOH. comprises of about 4% to about 5% of said forth solution.

- 44. The method of claim 2, wherein said forth period comprises 10 minutes.
- 45. The method of claim 2, wherein said forth solution comprises H_2O_2
- 46. The method of claim 2, wherein said first set of alkalines comprises NH₄OH.
- 47. The method of claim 46, wherein said NH₄OH comprises from about 8% to about 33% of said fifth solution.
- 48. The method of claim 46, wherein said NH₄OH comprises from about 6% to about 33% of said fifth solution.
- 49. The method of claim 46, wherein said NH₄OH comprises of about 25% of said fifth solution.
- 50. The method of claim 2, wherein said forth solution comprises H₂O₂.
- 51. The method of claim 50, wherein said H_2O_2 comprises from about 8% to about 33% of said fifth solution.
- 52. The method of claim 50, wherein said H_2O_2 comprises from about 6% to about 33% of said fifth solution.
- 53. The method of claim 50, wherein said H_2O_2 comprises of about 25% of said fifth solution.
- 54. The method of claim 2, wherein said fifth period comprises 10 minutes.
- 55. In a plasma processing system, a method of removing a set of particles from a set of structures including yttrium oxide, comprising:

exposing said set of structures to a first solution including a keytone reagent for a first period;

removing said set of structures from said first solution;

exposing said set of structures to a second solution including an oxidizer for a second period;

removing said set of structures from said second solution; and mechanically rubbing a surface of said set of structures with a third solution including a first set of acids for a third period.

56. The method of claim 55, further including the steps of:

exposing said set of structures to a fourth solution including a second set of acids for a fourth period; and

exposing said set of structures to a fifth solution including a first set of alkalines for a fifth period.

57. In a plasma processing system, a method of removing a set of particles from a set of structures including yttrium oxide, comprising:

exposing said set of structures to a first solution including an oxidizer for a first period;

exposing said set of structures to a second solution including a first set of alkalines with said oxidizer for a second period;

removing said set of structures from said second solution; and mechanically rubbing a surface of said set of structures with said third solution including a first set of acids for a third period.

58. The method of claim 57, further including the step of exposing said set of structures to a solution including a second set of acids for a fourth period.